

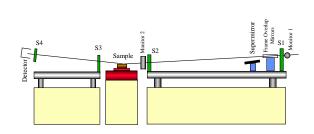
ISIS Neutron Scattering Training Course: Large Scale

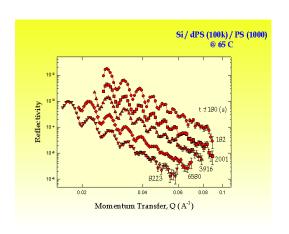
Structures Module : May 2010

Introduction to Neutron Reflectivity

J.R.P. Webster

ISIS Facility, Rutherford Appleton Laboratory



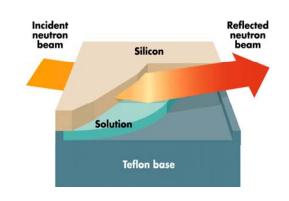




Specular reflection of neutrons from surfaces and interfaces

Analagous to optical interference, ellipsometry

Equivalent to electromagnetic radiation with electric vector perpendicular to the plane of incidence





Depth Profiling: provides information on concentration or composition profile perpendicular to the surface or interface

(Penfold, Thomas, J Phys Condens Matt, 2 (1990)1369, T P Russell, Mat Sci Rep 5 (1990) 171)



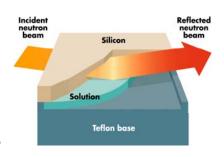
Reflectometry

Kinetics

- ■Polymer Diffusion
- Critical exponents in SCF
- Protein unfolding
- Non equilibrium surfactant films
- ■Temporal resolution of
 - ■Ion transfers
 - ■Solvent transfers
 - ■Polymer structure

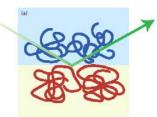
Electrochemistry

- Electrodeposition and Surface nucleation
- Self Assembly of systems
 - Metal Hydroxide electroprecipitation (batteries)
 - Novel templating mechanisms



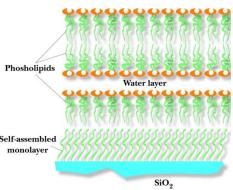
Model Devices

- ■Thin polymer films (finite size effects)
- Spin coating



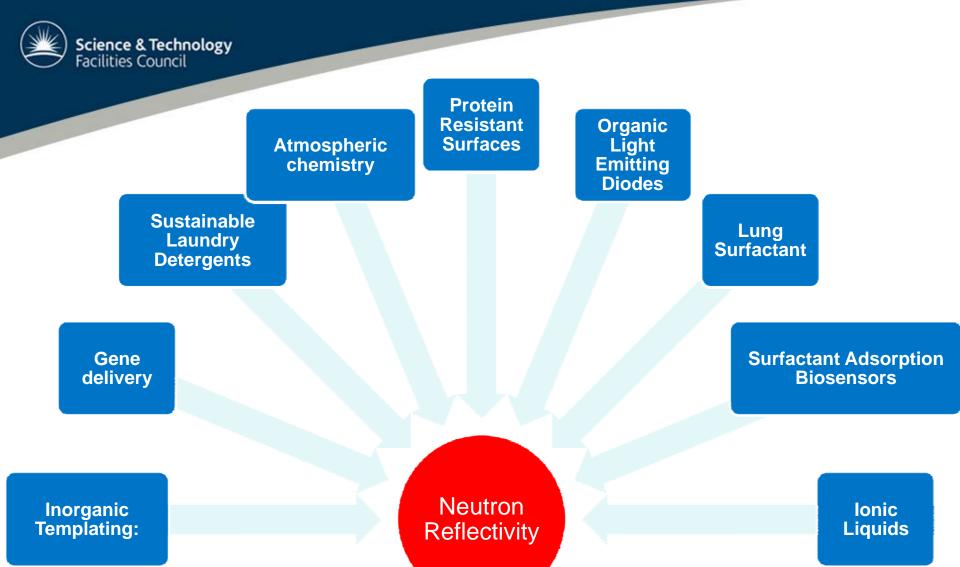
Surfactants

- Parametric Studies
- Liquid/Liquid Interface
- Reduce Label size in Structural Studies
- Self Assembly
- Foams



Biology

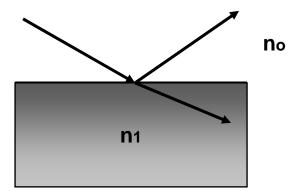
- Protein adsorption
- •Biocompatible polymers
- Drug transport
- Anaesthesia mechanisms



Specular reflection of neutrons

Refractive index defined using the usual convention in optics:

$$n = k_1 / k_0$$



$$n = 1 - \lambda^2 A - i \lambda B$$

$$A = \frac{Nb}{2\pi}$$

$$B = \frac{N(\sigma_a + \sigma_i)}{4\pi}$$

X-rays

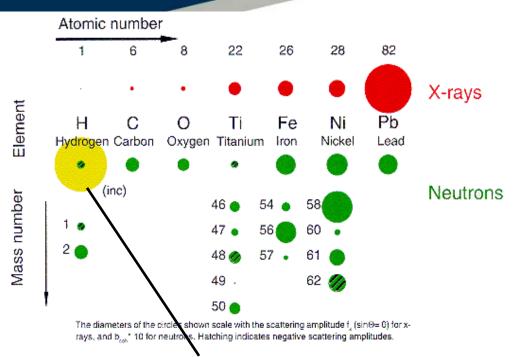
$$n = 1 - \alpha - i\beta$$

$$\alpha = N\lambda^{2} Z re/2\pi$$

$$\beta = \lambda \mu/4\pi$$



Refractive Index for neutrons

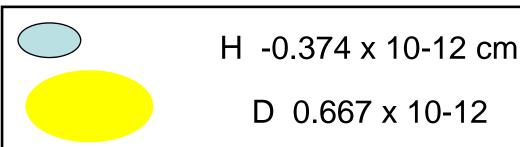


$$n = \frac{k_1}{k_0}$$

$$n = 1 - \lambda^2 A - i\lambda B$$

$$A = \frac{N b}{2 \pi}$$

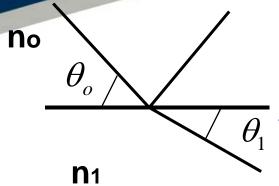
Extensively use H/D isotopic substitution to manipulate "contrast" or refractive index



n < 1.0 hence TOTAL EXTERNAL REFLECTION



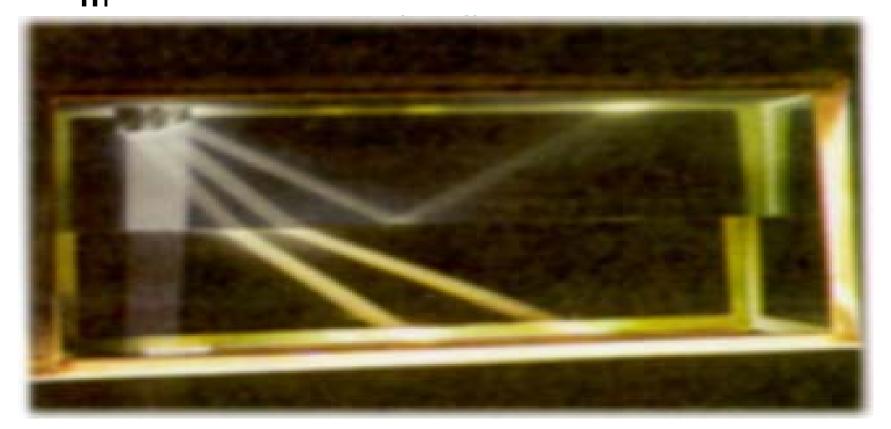
Specular reflection of neutrons (some basic optics)



From Snell's Law,
$$n = \frac{n_1}{n_0} = \frac{\cos \theta_0}{\cos \theta_1}$$

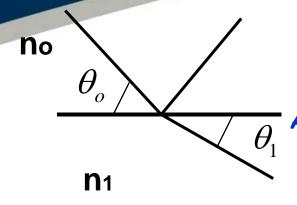
At total reflection
$$\theta_0 = \theta_c$$

$$\theta_1 = 0.0 \qquad \cos \theta_1 = 1.0$$





Specular reflection of neutrons (some basic optics)



From Snell's Law,
$$n = \frac{n_1}{n_0} = \frac{\cos \theta_0}{\cos \theta_1}$$

At total reflection
$$\theta_0=\theta_c$$

$$\theta_1=0.0 \qquad \cos\theta_1=1.0$$

Critical angle

$$\cos\theta_c = 1 - Nb \frac{\lambda^2}{2\pi}$$

$$\theta_c = \lambda \sqrt{\frac{Nb}{\pi}}$$

Total reflection (R=1.0) for $\theta < \theta_c$

For
$$\theta > \theta_c$$
 Fresnel's Law

$$\frac{1}{n_0} \frac{1}{\sin \theta_1} \frac{1}{\sin \theta_1} = \left(n_1^2 - n_0^2 \cos \theta_0^2\right)^{\frac{1}{2}}$$

$$R = \left| \frac{n_0 \sin \theta_0 - n_1 \sin \theta_1}{n_0 \sin \theta_0 + n_1 \sin \theta_1} \right|^2$$

$$n_1 \sin \theta_1 = \left(n_1^2 - n_0^2 \cos \theta_0^2\right)^{\frac{1}{2}}$$

$$n_1 \sin \theta_1 = \left(n_1^2 - n_0^2 \cos \theta_0^2\right)^{1/2}$$

 $\theta < \theta_c \; n_1 \sin \theta_1$ is imaginary (Evanescent wave)

$$\theta > \theta_c$$
 $n_1 \sin \theta_1$ Is real, and zero at $\theta = \theta_c$



Some typical values for θ_c and σ_a

Material	θ _c (deg / Å)
Ni	0.1
Si	0.047
Cu	0.083
Al	0.047
D₂O	0.082

Material	σ _α (barns)
Si	0.17
Cu	3.78
Co	37.2
Cd	2520
Gd	29400



Incident neutron beam Silicon Solution Teflon base

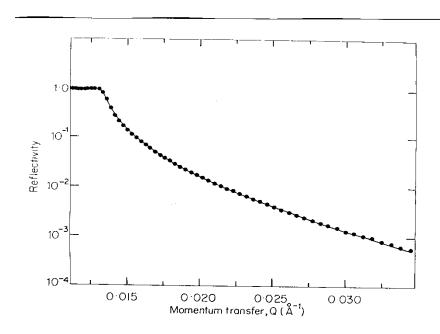
Specular Neutron Reflection (simple interface)

Within Born Approximation the Reflectivity is given as,

$$R(Q) = \frac{16\pi^2}{Q^4} \left| \int \rho'(z) e^{-iQz} dz \right|^2$$

$$Q = k_{1} - k_{2} = 4\pi \sin \theta / \lambda$$

Reflectivity from a simple single interface is then given by Fresnels Law



$$R = \left| \frac{n_0 \sin \theta_0 - n_1 \sin \theta_1}{n_0 \sin \theta_0 + n_1 \sin \theta_1} \right|^2$$

$$R(Q) = \frac{16\pi^2}{Q^4} \Delta \rho^2$$



Specular Neutron Reflection

For thin films see interference effects that can be described using standard thin film optical methods

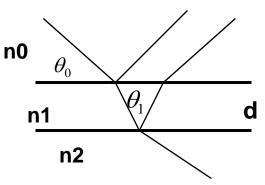
For a single thin film at an interface

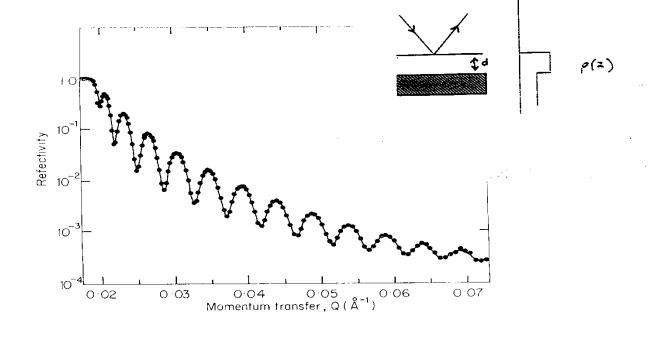
$$R(Q) = \left| \frac{r_{01} + r_{12} e^{-2i\beta}}{1 + r_{01} r_{12} e^{-2i\beta}} \right|^{2}$$

$$r_{ij} = \frac{\left(p_i - p_j\right)}{\left(p_i + p_j\right)}$$

$$p_i = n_i \sin \vartheta$$

$$\beta_i = \frac{2\pi}{\lambda} n_i d_i \sin \theta_i$$





For a single thin film:

$$R(Q) = \frac{r_{01}^2 + r_{12}^2 + 2r_{01}r_{12}\cos 2n_1k_1d_1}{1 + r_{01}^2r_{12}^2 + 2r_{01}r_{12}\cos 2n_1k_1d_1}$$

For $Q >> Q_c$:

$$R(Q) \sim \frac{16\pi^2}{Q^4} \left[(\rho_1 - \rho_0)^2 + (\rho_2 - \rho_1)^2 + 2(\rho_1 - \rho_0)(\rho_2 - \rho_1)\cos(Qd) \right]$$

Fourier transform of 2 delta functions (young's slits)

FRINGE SPACING:

$$\Delta Q = \frac{2\pi}{d}$$



Rough or Diffuse Interface

For a simple interface reflectivity modified by,

$$R = R_0 \exp(-q_0 q_1 \sigma^2)$$

 $q_i = 2k \sin \theta_i$ $k = \frac{2\pi}{\lambda}$

o is rms Gaussian roughness

Gaussian factor (like Debye-Waller factor) results in larger that q^{-4} dependence in the reflectivity.

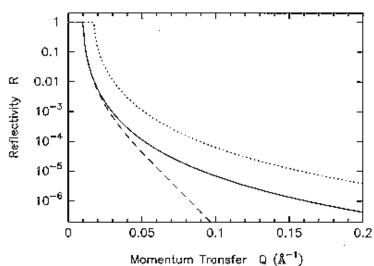
(Nevot, Croce, Rev Phys Appl 15 (1980) 125, Sinha, Sirota, Garoff, Stanley, Phys Rev B 38 (1988) 2297)

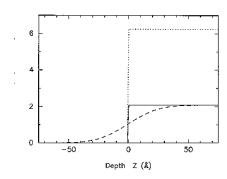
Can be also applied to reflection coefficents in formulism for thin films,

$$r_{ij} = \frac{(p_i - p_j)}{(p_i - p_j)} \exp(-0.5(q_i q_j \sigma^2))$$

From specular reflectivity cannot distinguish between roughness and diffuse interface

Reflectivity from a simple interface





Effect of roughness and sld

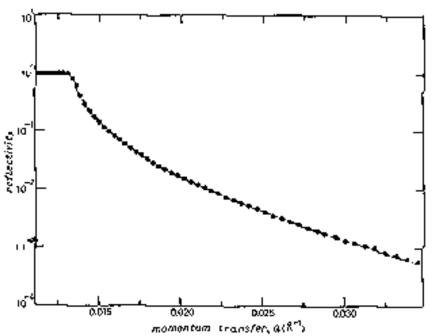
Glass optical flat

$$\theta = 0.35$$

$$Nb = 0.35 \times 10^{-5} \,\mathrm{A}^{-2}$$

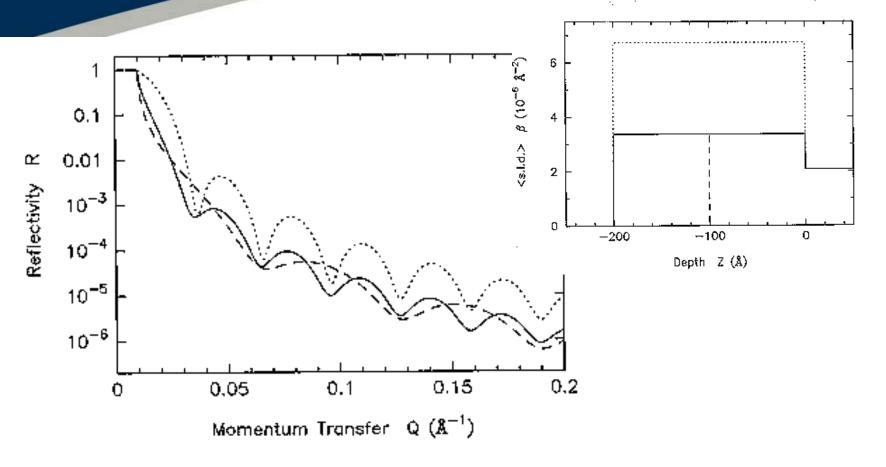
$$\sigma = 33A$$

$$\Delta\theta = 5\%$$

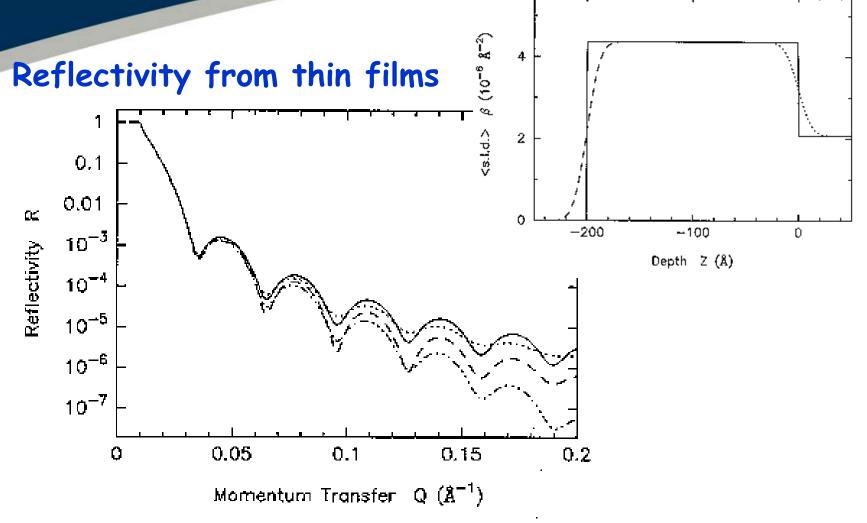




Reflectivity from thin films

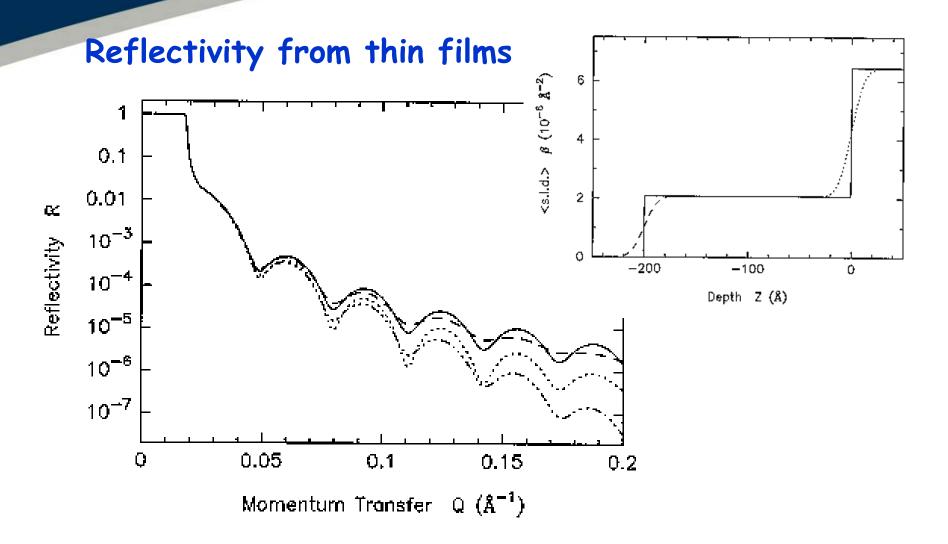


Effect of film thickness and refractive index



Effect of interfacial roughness





Effect of interfacial roughness

10⁻¹ 10⁻³ 10⁻³ 10⁻⁴ 0.02 0.03 0.04 0.05 0.06 0.07 Momentum transfer, Q (Å⁻¹)

Deuterated L-B film on silicon

$$d = 1198A$$

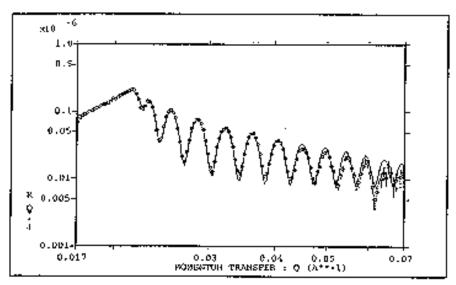
 $Nb = 0.74x10^{-5} A^{-2}$
 $\theta = 0.5, \Delta \theta = 4\%, \sigma = 20A$

Reflectivity from a thin film

NiC film on silicon

$$d = 1194A, Nb = 0.94x10^{-5} A^{-2}$$

 $\theta = 0.5, \Delta \theta = 4\%, \sigma_1 = 10, \sigma_2 = 15A$

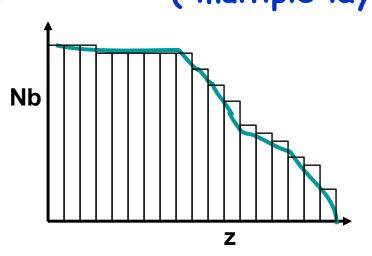


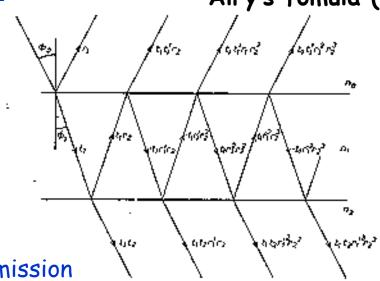


Reflection from more complex interfaces (multiple layers)

Airv's fomula







Combination of reflection and transmission \ coefficients give amplitude of successive beams reflected,

$$r_1, t_1t_1r_2, -t_1t_1r_1r_2^2, t_1t_1r_1^2r_2^3$$
 and so on

(Parratt, Phys Rev 95 91954) 359 G B Airy, Phil Mag 2 (1833) 20)

Phase change on traversing film, $\delta_1 = \frac{2\pi}{\lambda} n_1 d_1 \sin \theta_1$

$$R = r_1 + t_1 t_2 r_2 e^{-2i\delta_1} - t_1 t_1 r_1 r_2^2 e^{-4i\delta_1} + \dots$$

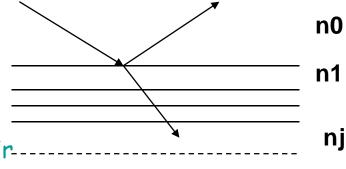
More general matrix formulisms (Born & Wolf, Abeles) available



Reflection from multiple layers

Born and Wolf matrix formulism

Applying conditions that wave functions and theirgradients are continous at each boundary gives rise to a **Characteristic matrix** per layer,



ns

$$Mj = \begin{bmatrix} \cos \beta_j & -(i/p_j)\sin \beta_j \\ -ip_j \sin \beta_j & \cos \beta_j \end{bmatrix}$$

(Born & Wolf, 'Principles in Optics', 6th Ed, Pergammon, Oxford, 1980)

$$p_{j} = n_{j} \sin \theta_{j}$$
$$\beta_{j} = (2\pi/\lambda)n_{j}d_{j} \sin \theta_{j}$$

$$M_R = [M_1][M_2] - - - [M_n]$$

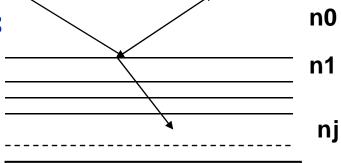
The resultant reflectivity is

$$R = \left[\frac{\left(M_{11} + M_{12} p_s \right) p_a - \left(M_{21} + M_{22} \right) p_s}{\left(M_{11} + M_{12} p_s \right) p_a + \left(M_{21} + M_{22} \right) p_s} \right]^2$$



Reflection from multiple layers

In Born and Wolf approach can only include roughness / diffusiveness at interfaces by further sub-division in small layers.



ns

Abeles method, using reflection coefficients overcomes this limitation

Define characteristic matrix per layer, in optical terms from the relationship between electric vectors in successive layers,

$$C_{j} = egin{bmatrix} e^{ieta_{j-1}} & r_{j}e^{ieta_{j-1}} \ r_{j}e^{-ieta_{j-1}} & e^{-ieta_{j-1}} \end{bmatrix}$$

(Heavens, 'Optical properties of solid thin films', Butterworths, London, 1955, F Abeles, Annale de Phys 5 (1950) 596)

The resultant Reflectivity is then,

$$\begin{bmatrix} C_1 \end{bmatrix} \cdot \begin{bmatrix} C_2 \end{bmatrix} - - - - \begin{bmatrix} C_{n+1} \end{bmatrix} = \begin{bmatrix} a & b \\ c & d \end{bmatrix}$$

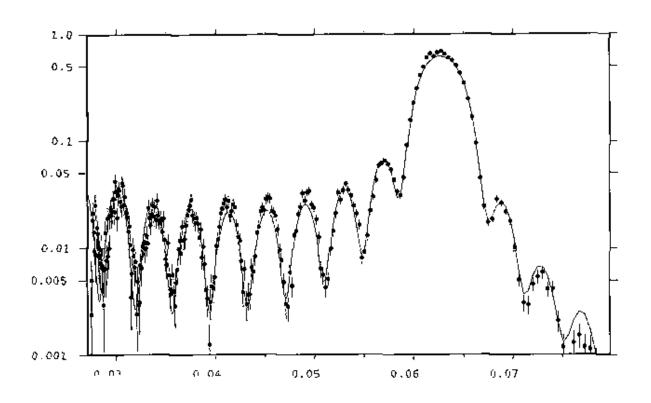
To include roughness,

$$r_{j} = \frac{\left(p_{j-1} - p_{j}\right)}{\left(p_{j-1} + p_{j}\right)} \exp\left(-0.5q_{j}q_{j-1}\sigma^{2}\right)$$

$$R = CC^* / AA^*$$

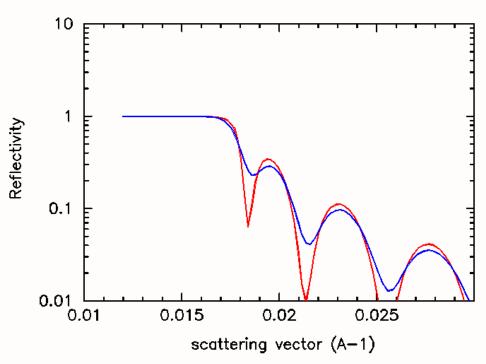


Multiple Layer films



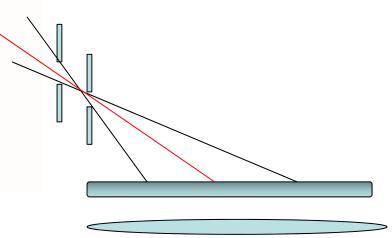
Region around 1st order Bragg peak for Ni/Ti multilayer 15 bilayers (46.7, $1.0 \times 10-5$ / 55.7, $-0.13\times10-5$)

Effects of resolution



$$\frac{\Delta Q^2}{Q^2} = \frac{\Delta t^2}{t^2} + \frac{\Delta \theta^2}{\theta^2}$$

On SURF and CRISP resolution is dominated by collimation

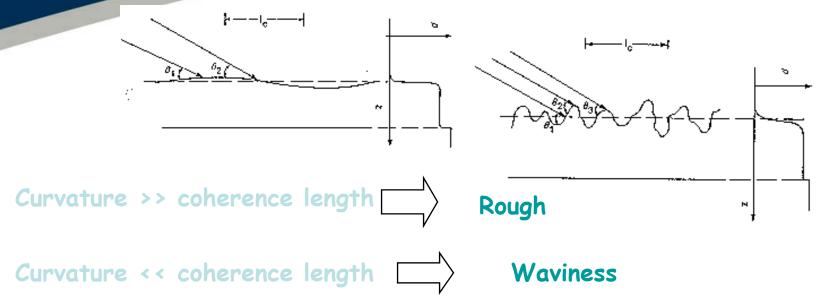


1000 Å film on Si , $\Delta Q/Q$ 2%, 6%

Damps interference fringes, rounds critical edge



Surface roughness and Waviness

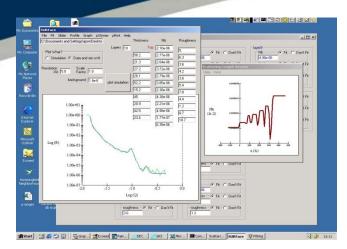


This initially has an effect similar to resolution, and in the extreme can be treated by geometrical optics.

Incoherent reflectivity from 2 surfaces, separated by an adsorbing media:

$$R_{tot}(Q) = R_1(Q) + \frac{(1 - R_1(Q))^2 R_2(Q) A(Q)}{1 - R_1(Q) R_2(Q) A(Q)}$$





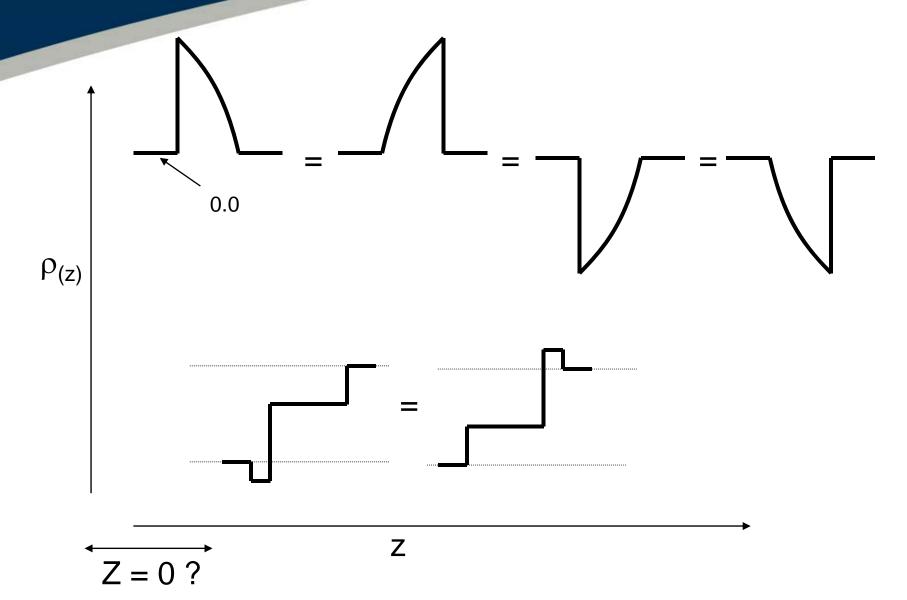
Scattering length reflectivity — density

Steepest decent, simplex, simulated annealing, genetic, cubic spline + fft, etc etc

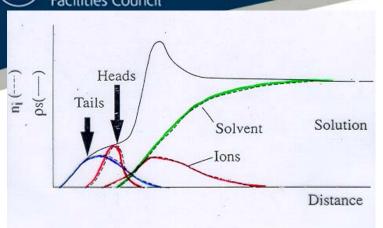
Model fitting Reflectivity data

- Uniqueness ?
- •Resolution ?
- Model dependent / overinterpretation of data ?
- Does the scattering length density profile give access to the necessary physical parameters (Intra molecular)
 ?

Lateral (z) and rotational invariance







Partial Structure Factors

$$R(\kappa) = \frac{16\pi^2}{\kappa^2} \left| \int_{-\infty}^{+\infty} \rho(z) e^{-i\kappa z} dz \right|^2$$

$$\rho(z) = b_c n_c(z) + b_h n_h(z) + b_s n_s(z)$$

$$R(\kappa) = \frac{16\pi^2}{\kappa^2} \left[b_c^2 h_{cc} + b_h^2 h_{hh} + b_s^2 h_{ss} + 2b_c b_h h_{ch} + 2b_c b_s h_{cs} + 2b_h b_s h_{hs} \right]$$

Self Partial Structure Factors : $h_{ii} = \left| \hat{n}_i \right|^2$

 \hat{n}_i is a one dimensional Fourier transform of $n_i(z)$

Cross partial structure factors:

$$h_{ij} = \text{Re}\Big\{\hat{n}_i \hat{n}_j\Big\}$$

(Crowley, Lee, Simister, Thomas, Penfold, Rennie, Coll Surf 52 (1990) 85)



Cross Partial Structure Factors

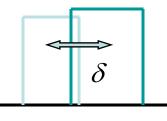
If one distribution is shifted by $\,\delta\,\,\,\,$ Fourier transform is changed by phase factor $\exp(i\kappa\delta)$

$$\hat{n}_{i}(z) = n_{i}(z - \delta)$$

$$\hat{n}_{i}(\kappa) = n_{i}(\kappa) \exp(i\kappa\delta)$$

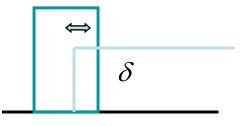
$$h_{ij} = \text{Re} \{ \hat{n}_i \hat{n}_j \} \exp(i \kappa \delta_{ij})$$

If both even functions



$$h_{ij} = \pm \left[h_{ii} h_{jj} \right]^{1/2} \cos i \kappa \delta$$

If even + odd functions



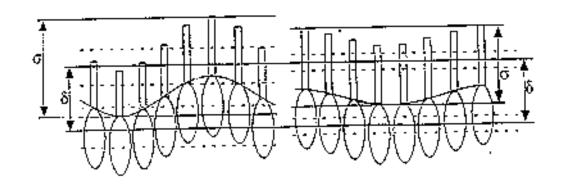
$$h_{ij} = \pm \left[h_{ii}h_{jj}\right]^{1/2} \sin i\kappa \delta$$

 \pm because of phase uncertainty

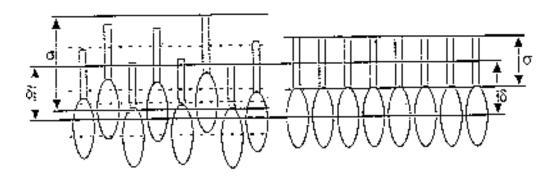
Model Self-terms as Gaussian (solvent as tanh)



Effect of capillary wave and structural roughness on cross-terms



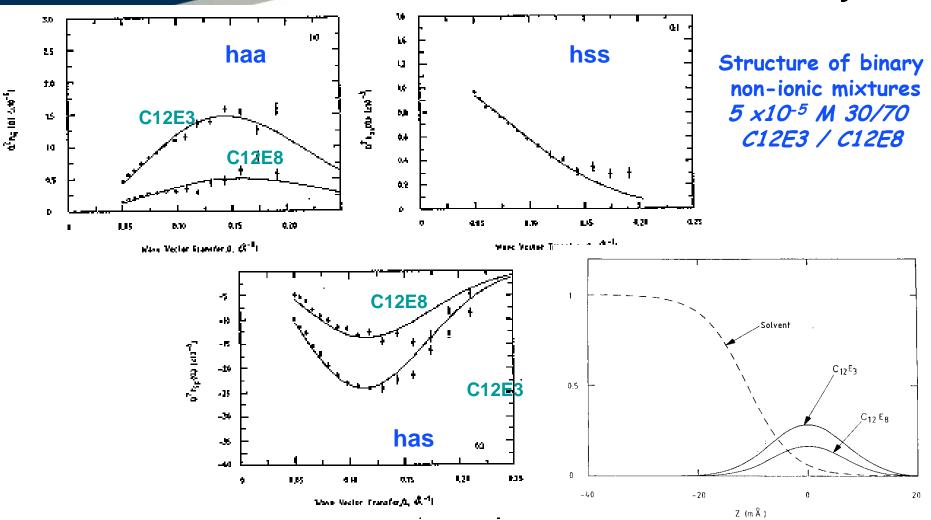
Widths of individual distributions affected by roughness,



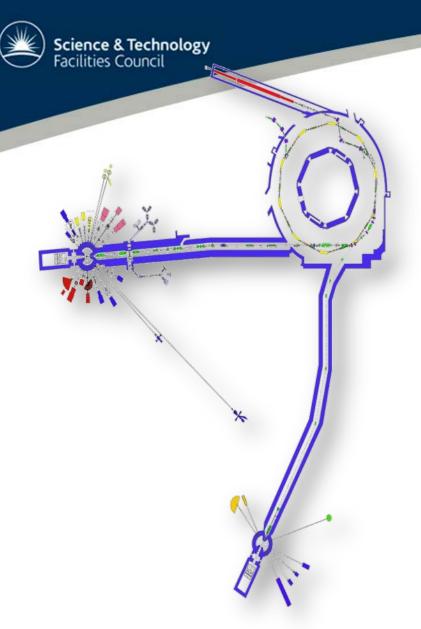
but separations are NOT



Partial Structure Factor Analysis



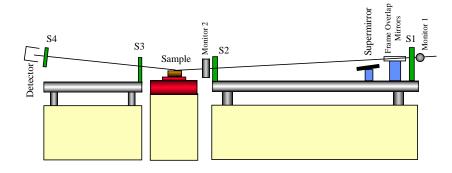
Example of simplest labelling scheme : solvent, alkyl chain of each surfactant



Neutron Reflectivity at ISIS

Measure variation of reflectivity with scattering vector, Qz, perpendicular to the interface

Using 'white beam' TOF method with fixed angle and range of wavelengths



INTER, POLREF, OFFSPEC, SURF, CRISP reflectometers

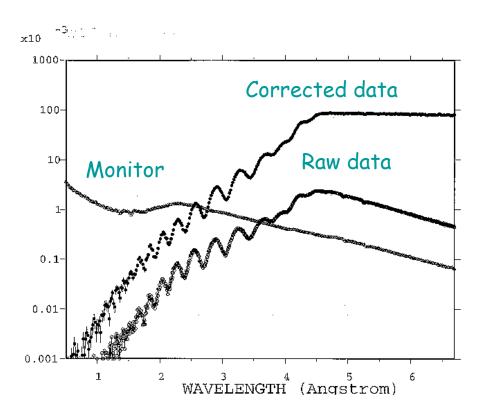
(Penfold, Williams, Ward, J Phys E 20 91987) 1411; J Penfold et al, J Chem Soc, Faraday Trans, 94 (1998) 955



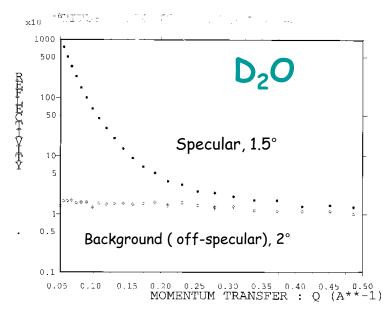
Instrumentation

Correct for detector efficiency, spectral shape, background

$$R\left(Q\left(\lambda_{i},\theta\right)\right) = f\left[\frac{\left[I_{d}\left(\lambda_{i}\right) - b_{d}\left(\lambda_{i}\right)\right]}{\left[I_{m}\left(\lambda_{i}\right) - b_{m}\left(\lambda_{i}\right)\right]} \frac{\varepsilon_{m}\left(\lambda_{i}\right)}{\varepsilon_{d}\left(\lambda_{i}\right)}$$

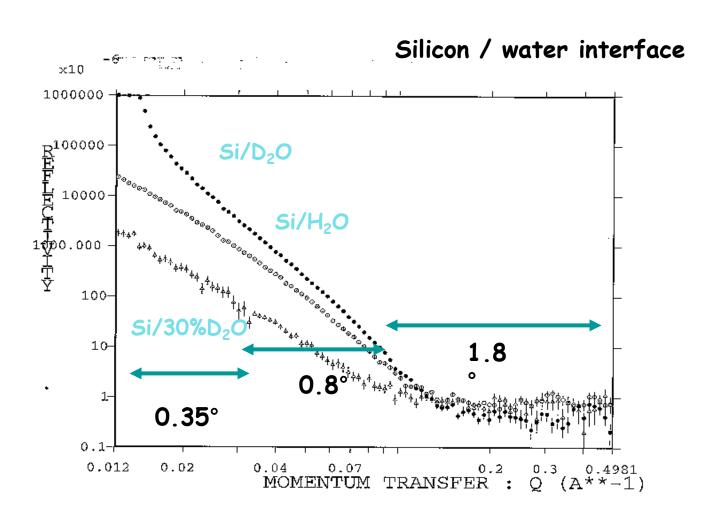


d,m refer to the detector and monitor





Instrumentation









Designed for the study of chemical interfaces, with a particular emphasis on the air-water interface

>10 times the flux of SURF

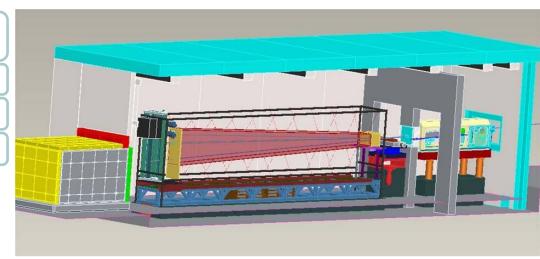
Much wider dynamic range

Tuneable resolution

Scientific Opportunities

- Biology
 - Cell adhesion using synthetic polymer analogues
 - Kinetics of action of interfacial enzymes
 - Interfacial structure of designed peptides (folding)
 - Biofouling and adsorption kinetics
 - Interlayer forces in polymer and biological systems
 - Supported bilayers
- Polymer diffusion

Inter



wavelength range	1 – 16 (22) Å
Moderator	Coupled s-CH ₄ grooved – 26K
Primary flight path	19m (m=3 supermirror guides)
Secondary flight path	3-8 m
Beam size	60(h) x 30(v) mm
Flux at sample	~10 ⁷ n/s/cm ²



Designed for the study of chemical interfaces, with a particular emphasis on the air-water interface

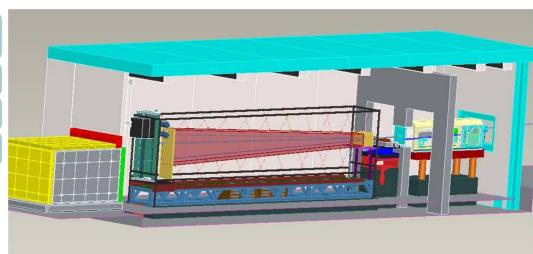
>10 times the flux of SURF

Much wider dynamic range

Tuneable resolution



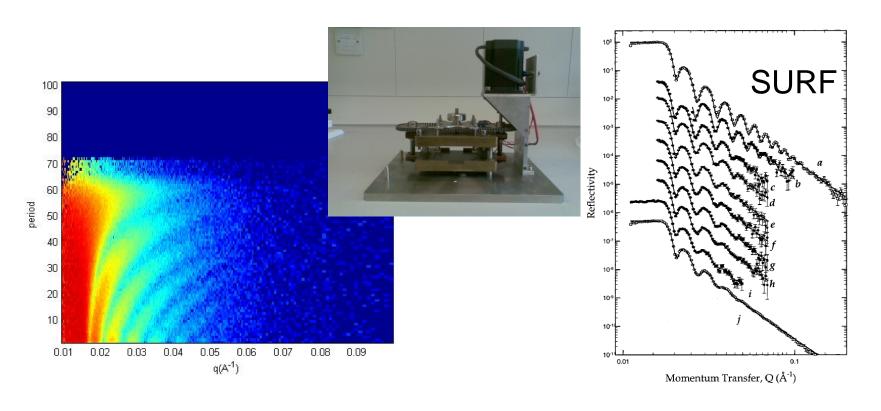
Inter



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Flux at sample	~10 ⁷ n/s/cm ²



Kinetic data from INTER





Uses polarised neutrons to study the inter an intra-layer magnetic ordering in thin films and surfaces

>20 times the flux of CRISP

Much wider dynamic range

Flexible polarisation

Dual Geometry

High precision sample stage

Scientific Opportunities

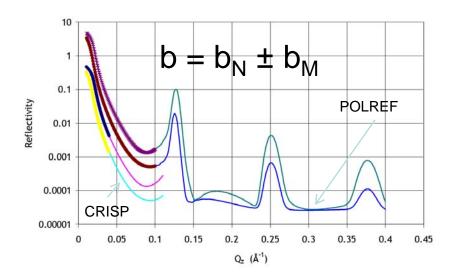
Spin Electronics

- Spin-Injection
- Spin Torque
- Dilute magnetic semiconductors
- Giant/Tunnelling magneto-resistance

Model Magnetic Systems

- Ultrathin films (finite size effects)
- Exchange springs (domain walls, surface magnetic phase transitions)
- Stabilise new single-crystal phases (Ce, Mn,..)

PolRef



wavelength range	0.9 – 16 Å
Moderator	Coupled s-CH ₄ grooved – 26K
Primary flight path	23m
Secondary flight path	3 m
Beam size	60(h) x 30(v) mm
Flux at sample	~10 ⁷ n/s/cm ²



Science & Technology

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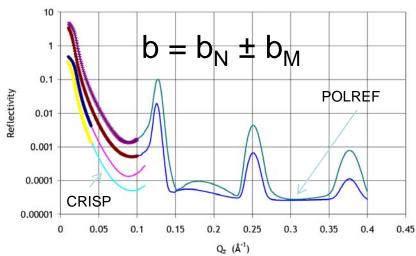
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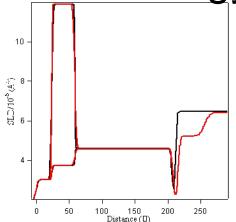


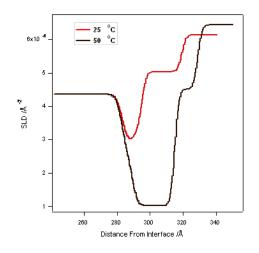
Polarised Neutrons for Biology

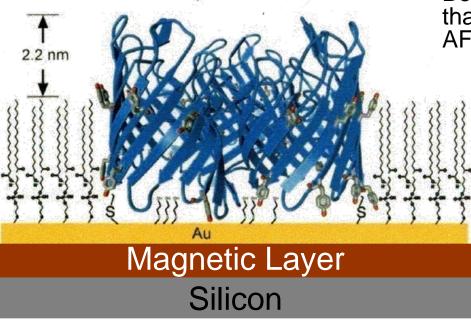
Use polarised neutrons to provide additional information for protein absorption

 Extract protein thickness and orientation

 Better resolution than conventional AFM studies

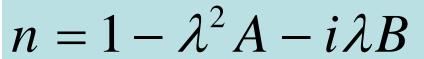




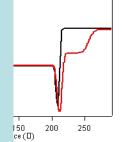


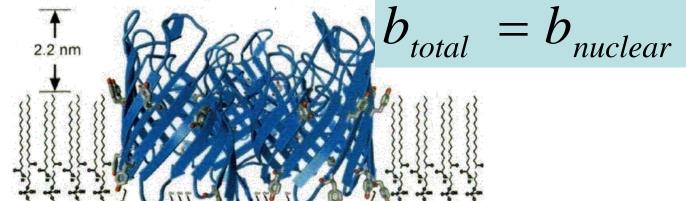


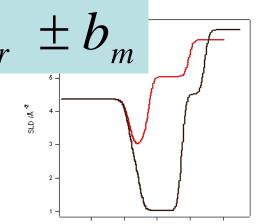
Polarised Neutrons for Biology



$$A = \frac{Nb}{2\pi}$$







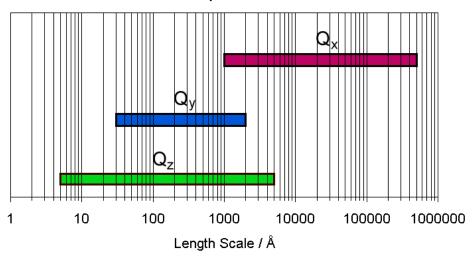
Distance From Interface /A

Magnetic Layer Silicon



Neutron Spin-Echo

In-plane dynamic range of 50Å-42 μ m



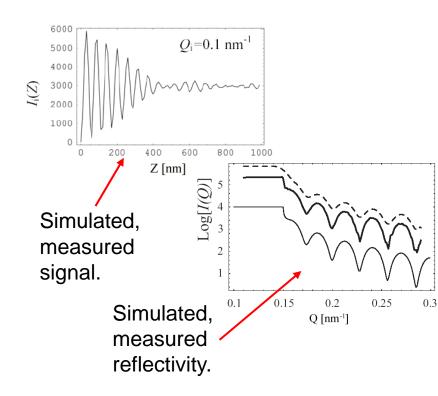
Scientific Opportunities

In-plane Structures

- Patterned Storage Media
- Mesoporous films
- Polymers
- Biological membranes
- Surfactants

Grazing Incidence Diffraction

- Surface crystalline structure
- Surface phase transitions
- Magnetic surface structure

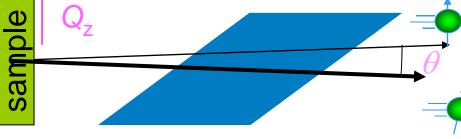




Larmor precession codes

scattering angle





Unscattered beam gives spin echo (net precession) Independent of height and angle

$$\phi = 0$$

Scattering by sample over angle *q* results in a net precession

$$\phi = c\lambda BL \cot(\theta_0) \theta \approx zQ_z$$

Proportional to the **spin echo length** *z*

$$z = c\lambda^2 BL \cot(\theta_0)/2p$$

Measure polarisation

$$\frac{P}{P_0} = \int d\Omega \cos \phi f(\phi) \approx \int dQ_x dQ_y dQ_z \cos(\mathbf{z}Q_z) S(Q)$$

Keller *et al.* Neutron News **6**, (1995) 16 Rekveldt, NIMB **114**, 366 (1996)



5 modes of operation

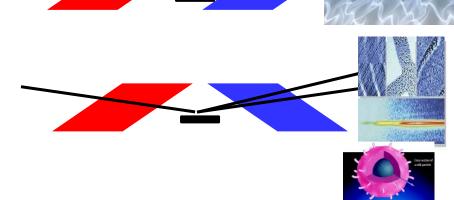
SE reflection measurements to probe in plane structure

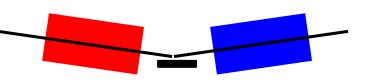
SE reflectivity with "high resolution" at low q and "wavy surface"

Spin-echo reflection "separation" of specular and off-specular reflection

Spin echo small angle scattering in transmission (SESANS)

Classical Spin echo in transmission or reflection of inelastic samples







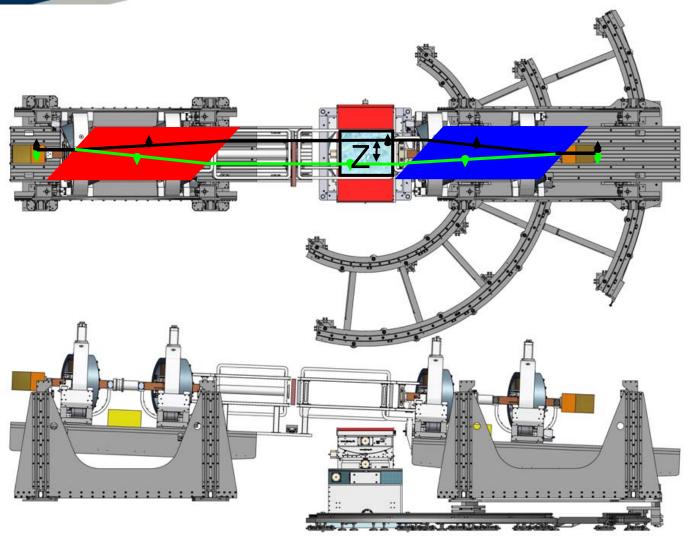
Realisation/Design

Nov 05





Realisation/Design



Aug 08



Realisation/Design



May 09